



Fig. S1 (a) Cross-section TEM image and ED pattern of rutile-type  $\text{TiO}_x$  thin films. (b)  $I$ - $V$  characteristics of 100 nm-thick  $\text{TiO}_x$  thin films, measured at a voltage sweep rate of 100  $\text{V s}^{-1}$  (—), 1  $\text{V s}^{-1}$  (—) and 0.01  $\text{V s}^{-1}$  (—).